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	for form 144			Complete if Known		
INI	INFORMATION DISCLOSURE			Application Number	10/018,406	
STATEMENT BY APPLICANT				Filing Date	December 13, 2001	
	(use as many sheets as necessary)			First Named Inventor	Charles E. Wickersham, Jr.	
				Art Unit	1742	
				Examiner Name		
Sheet	1	of	4	Attorney Docket Number	TSO 190 P2	

			U.S. PATENT	DOCUMENTS		
Examiner Initials*	Cite No.	<u>Document Number</u> Number - Kind Code <sup>2</sup> (if known)	Publication Date MM-DD-YYYY		Pages, Columns, Lines, Who Relevant Passages or Releva Figures Appear	
ma		US-2,790,216	4-30-1957	Hunter		
ma		US-4,054,173	10-18-1977	Hickam	^	
ma		US-4,568,007	2-4-1986	Fishler	TEO.	
ma		US-5,160,388	11-3-1992	Legresy et al.	PROSINGED	
ma		US-5,369,063	11-29-1994	Gee et al.	3200	
mà		US-5,406,850	4-18-1995	Bouchard et al.	1700	
ma		US-5,559,614	9-24-1996	Urbish et al.	00	
ma		US-5,636,681	6-10-1997	Sulzer et al.		
MA		US-5,738,767	4-14-1998	Coad et al.		
MA		US-5,827,409	10-27-1998	Iwata et al.		
		]	FOREIGN PATE	ENT DOCUMENTS		
Examiner Initials*	Cite No.1	Foreign Patent Document Country - Number <sup>4</sup> -KindCode <sup>5</sup> Code <sup>3</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Т
ma		EP 0 211 401 B1	05-06-1992	General Electric Company		
ma		EP 0 418 846 B1	02-08-1995	Honeywell, Inc.		
ma		EP 0 665 193 A2	08-02-1995	Intevac, Inc.		
MA		EP 0 467 659 B1	03-06-1996	Sharp Kabushiki Kaisha		

	Examiner Signature	melvyn	andrews	Date Considered	11-20-03
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¹Applican'ts unique citation designation number (optional). ²See Kinds Codes of USPTO Patent Documents at <a href="https://www.uspto.gov">www.uspto.gov</a> or MPEP 901.04.
³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

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Substitute for form 1449A/PTO	Complete if Known		
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STATEMENT BY APPLICANT	Filing Date	December 13, 2001	
(use a many steets as necessary)	First Named Inventor	Charles E. Wickersham, Jr.	
MAR 2 9 2002 &	Art Unit	1742	
P. C.	Examiner Name		
Sheet 2 of 4	Attorney Docket Number	TSO 190 P2	

			U.S. PATENT I	OCUMENTS		
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ma		US-5,887,481	3-30-1999	Leroy et al.		
YELL		US-5,943,559	8-24-1999	Maeda		
ma		US-5,955,673	9-21-1999	Leroy et al.	An	
ma		US-5,989,782	11-23-1999	Nishiki et al.	CEI	
ma		US-6,001,227	12-14-1999	Pavate et al.	PROSVE	<b>`</b>
-	_	US-6,017,779	1 25 2000	Miyasaka DUPLICATE	APR 03 TOO	O
Ma		US-6,019,657	2-1-2000	Chakvorty et al.	1700	
ma		US-6,020,946	2-1-2000	Callegari et al.		
ma		US-6,057,557	5-2-2000	Ichikawa		
md		US-6,139,701	10-31-2000	Pavate et al.		
		FC	REIGN PATEN	T DOCUMENTS		
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document Country - Number 4-KindCode5 Code3 (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T'
ma		EP 0 412 843 B1	05-29-1996	Sharp Kabushiki Kaisha		
ma		EP 0 561 161 B1	04-23-1997	Corning Incorporated		
ma		WO 99/64854	12-16-1999	Tosoh SMD, Inc.		
ma		WO 00/15863	3-23-2000	Tosoh SMD, Inc.		
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<sup>3</sup> Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup>For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup>Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup>Applicant is to place a check mark here if English language Translation is attached.

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S'.	TATEMENT B			Filing Date	December 13, 2001	
	(use as main sheets as necessary)  MAR 2 9 2002			First Named Inventor	Charles E. Wickersham, Jr.	
				Art Unit	1752	
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Sheet	4	of	4	Attorney Docket Number	TSO 190 P2	

		OTHER PRIOR ART NON PATENT LITERATURE DOCUMENTS	
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- War		*BARNES, M.S. et al., <i>Phys. Rev. Letter</i> , (1992) 68, 313.	
* ~ ;		*GOREE J. et al., J. Vac. Sci. Techol., (1992) A10, 3540.	
		*NADEL, S.J. et al., 35th Tech. Conf. Proc. Society of Vacuum-Coaters, (1992) 365.	
		*ANDERSON, L., 35th Tech. Conf. Proc. Society of Vacuum Coaters, (1992) 325.	
		*SCHOLL, R.A., 37th Tech. Conf. Proc. Society of Vacuum Coaters, (1994) 312.	
11.		*BAILEY, R.S. et al., VMIC Conference, ISMIC, (1994) 317.	
,		*LEE, F. et al., Microcontamination, (1994) 12, 33.	
ma		DANOVICH, D. et al., "Sputtering Issues for Flat-Panel Displays," <i>Information Display</i> , (November 1995), pp. 26-27, 30-31.	
		*TAKAHASHI, K.M. et al., J. Vac. Sci. Technol., (1996), A14, 2983.	
		*SELWYN, G.S. et al., J. Vac. Sci. Technol, (1997) A15, 2023.	//
. 1		**TAKAHASHI, K.M. et al., J. Vac. Sci. Technol., (1996), A14, 2983.  **SELWYN, G.S. et al., J. Vac. Sci. Technol, (1997) A15, 2023.  **EERNISSE, E.P. et al., J. Appl. Phys., (1997) 48, 9!  -*MONTEIRO, O.R. et al., IEEE-Trans-Plasma-Science, (1999) 27, 1030.	K
		*MONTEIRO, O.R. et al., IEEE-TransPlasma-Science, (1999) 27, 1030.	
7		*ADBURI, M. et al., Solid State Technology, (1999) 42, 55.	
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	Examiner Signature	melon andflws	Date Considered	11-20-03
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Substitute for form 1449A/PTO	Complete if Known		
INFORMATION DISCLOSURE	Application Number	10/018,406	
STATEMENT BY APPLICANT	Filing Date	December 13, 2001	
(use as many sheet as necessary)	First Named Inventor	Charles E. Wickersham, Jr.	
MAR 2 9 2002 &	Art Unit	1752	
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Sheet 3 of 4	Attorney Docket Number	TSO 190 P2	

		OTHER PRIOR ART NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T <sup>2</sup>
		*SELWYN, G.S. et al., Appl.Phys. Letter, (1876) p. 57.	
		*V <del>ON GÜNTHERSCHULZE, A., Z. Physik, (1933) 86, 778</del> .	
. :		*FREITAG, W.O. et al., 2nd Symposium on Deposition of Thin Films by Sputtering, CVC, Rochester, NY, (June 1967) p. 92.	
		*ROBINSON, I.F. et al., J. Nuclear Mat., (1976) 63, 432.	
. 10/		*WEHNER, G.K., J. Vac. Sci. Techol., (1985) A3, 1821.	
		*ROTH, R.M. et al., Appl. Phys. Letter, (1985) 46, 253.	人.
		*SPEARS, K.G. et al., IEEE Trans. Plasma Sci., (1986) PS 14, 179.	YZ
		*WEHNER, G.K., J. Vac. Sci. Techol., (1985) A3, 1821.  *ROTH, R.M. et al., Appl. Phys. Letter, (1985) 46, 253.  *SPEARS, K.G. et al., IEEE Trans. Plasma Sci., (1986) PS 14, 179.  *SELWYN, G.S. et al., J. Vac. Sci. Technol., (1989) A7, 2758.	
11		*JELLUM, G.M. et al, <i>J. Appl. Phys.</i> , (1990) 67, 6490.	
,		*ANDERSON, H.M. et al., J. Applied Physics, (1990) 67, 3999.	
		*SELWYN, G.S. et al., <i>J. Vac. Sci. Techol.</i> , (1990) A8, 1726.	
		*AKARI, K. et al., Surf. Coatings & Technol., (1990) 43-44, 312.	
		*SMADI, M.M. et al., J. Vac. Sci. Techel., (1992) B10, 30.	
		*LOGAN, J.S. et al., J. Vac. Sci. Techol., (1992) A10, 1875.	
		*YOO, W.J. et al., Appl. Phys. Letter, (1992) 60, 1073.	
ma		FOSTER, H.I. et al., "A Modular Approach to Sputter Coating of Flat Panel Displays,"  Society of Vacuum Coaters 35th Annual Technical Conference (1992) pp. 357-361.	

Examiner Signature	melvyx	andrew	Date Considered	11-20-03
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Substitute Corform 149A/PTO SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Comple	ete if Known
			<b>IATION</b>	Application Number	10/018,406
			CANT	Filing Date	December 13, 2001
				First Named Inventor	Charles E. Wickersmam, Jr.
			sary)	Art Unit	1752 MAY
				Examiner Name	7 2 2002
Sheet	1	of	3	Attorney Docket Number	TSO 190 12 C 7
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OTHER PRIOR ART NON PATENT LITERATURE DOCUMENTS				
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T <sup>2</sup>	
ma		FREITAG, W.O. et al., "Diode Sputtering of Cermet Films," 2nd Symposium on Deposition of Thin Films by Sputtering, University of Rochester and Consolidated Vacuum Corporation, Rochester, NY, June 1967, pp. 92-96.		
ma		ROBINSON, J.E. et al., "Models for Chunk Sputtering," <i>Journal of Nuclear Materials</i> , 1976, Vol. 63, pp. 432-437, North-Holland Publishing Company.		
ma		EERNISSE, E.P. et al., "Role of Integrated Lateral Stress in Surface Deformation of He- Implanted Surfaces," <i>Journal of Applied Physics</i> , January 1, 1977, Vol. 48, No. 1, pp. 9-17, American Institute of Physics.		
ma		ROTH, R.M. et al., "Spatial Dependence of Particle Light Scattering in an RF Silane Discharge," <i>Appl. Phys. Letter</i> , February 1, 1985, Vol. 46, No. 3, pp. 253-255, American Institute of Physics.		
ma		WEHNER, G.K., "Cone Formation as a Result of Whisker Growth on Ion Bombarded Metal Surfaces," <i>J. Vac. Sci. Techol.</i> , July/August 1985, A 3 (4), pp. 1821-1835, American Vacuum Society.		
ma		SPEARS, K.G. et al., "Particle Distributions and Laser-Particle Interactions in an RF Discharge of Silane," <i>IEEE Transactions on Plasma Science</i> , April 1986, Vol. PS-14, No. 2, pp. 179-187, IEEE.		
ma		SELWYN, G.S. et al., "In Situ Laser Diagnostic Studies of Plasma-Generated Particulate Contamination," J. Vac. Sci. Technol., July/August 1989, A 7, (4) pp. 2758-2765, American Vacuum Society.		
ma		ANDERSON, H.M. et al., "Particulate Generation in Silane / Ammonia RF Discharges," J. Applied Physics, May 1, 1990, Vol. 67, No. 9, pp. 3999-4011, American Institute of Physics.		

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## Substitute for form 1449ATE Complete if Known 10/018,406 Application Number SUPPLEMENTAL INFORMATION **DISCLOSURE** December 13, 2001 Filing Date STATEMENT BY APPLICANT First Named Inventor (use as many sheets as necessary) 1752 **Art Unit Examiner Name** Sheet 2 of 3 Attorney Docket Number

OTHER PRIOR ART NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No.	Include name of the auther (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T <sup>2</sup>		
ma		JELLUM, G.M. et al, "Particulates in Aluminum Sputtering Discharges," J. Appl. Phys., May 15, 1990, Vol. 67 No. 10, pp. 6490-6496, American Institute of Physics.			
ma		SELWYN, G.S. et al., "In situ Plasma Contamination Measurements by HeNe Laser Light Scattering: A Case Study," J. Vac. Sci. Techol., May / June 1990, A 8, (3) pp. 1726-1731, American Vacuum Society.			
ma		SELWYN, G.S. et al., "Particle Trapping Phenomena in Radio Frequency Plasmas," <i>Appl. Phys. Letter</i> , October 29, 1990, Vol. 57, No. 18 pp. 1876-1878, American Institute of Physics.			
Ma		AKARI, K. et al., "Reduction in Macroparticles During the Deposition of TiN Films Prepared by Arc Ion Plating," <i>Surface and Coatings Technology</i> , 1990, 43/44, pp. 312-323, Elsevier Sequoia, The Netherlands.			
ma		BARNES, M.S. et al., "Transport of Dust Particles in Glow-Discharge Plasmas," <i>Physical Review Letters</i> , January 20, 1992, Vol. 68, No. 3, pp. 313-316, The American Physical Society.			
ma		SMADI, M.M. et al., "Particle Contamination on a Silicon Substrate in a SF <sub>6</sub> / Ar Plasma," <i>J. Vac. Sci. Techol.</i> , January/February 1992, B 10, (1) pp. 30-36, American Vacuum Society.			
Ma		YOO, W.J. et al., "Kinetics of Particle Generation in Sputtering and Reactive Ion Etching Plasmas," <i>Appl. Phys. Letter</i> , March 2, 1992, Vol. 60, No. 9, pp. 1073-1075, American Institute of Physics.			
ma		LOGAN, J.S. et al.,"Study of Particle Emission in Vacuum from Film Deposits," <i>J. Vac. Sci. Techol.</i> , July/August 1992, A 10, (4) pp. 1875-1878, American Vacuum Society.			
ma		GOREE J. et al., "Particulate Release from Surfaces Exposed to a Plasma," J. Vac. Sci. Techol., November/December 1992, A 10, (6) pp. 3540-3544, American Vacuum Society.			

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## Substitute for form 1440A/PTO Complete if Known **Application Number** 10/018,406 SUPPLEMENTAL INFORMATION **DISCLOSURE Filing Date** December 13, 2001 STATEMENT BY APPLICANT First Named Inventor Charles E. Wickersham, Jr. (use as many sheets as necessary) **Art Unit** 1752 **Examiner Name** 3 3 Sheet of **Attorney Docket Number**

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me		ANDERSON, L., "A New Technique for Arc Control in DC Sputtering," Society of Vacuum Coaters 35th Annual Technical Conference Proceedings, 1992, pp. 325-329.		
ma		NADEL, S.J. et al., "Enhanced Chromium First Surface Mirrors," Society of Vacuum Coaters, 35th Annual Technical Conference Proceedings, 1992, pp. 365-369.	ı	
MA		SCHOLL, R.A., "A New Method of Handling Arcs and Reducing Particulates in DC Plasma Processing," Society of Vacuum Coaters 37th Annual Technical Conference Proceedings, 1994, pp. 312-315, Advanced Energy Industries, Inc.		
MA		LEE, F. et al., "Detecting and Reducing Particles for LPCVD Silicon Nitride Deposition," Microcontamination, March 1994, Vol. 12, pp. 33-37, 76-77.		
MA		BAILEY, R.S. et al., "Particle Emission from Al <sub>2</sub> O <sub>3</sub> Doped Aluminum Targets During Sputtering Deposition," VMIC Conference, ISMIC, June 7-8, 1994, p. 317.		
ma		TAKAHASHI, K.M. et al., "Current Capabilities and Limitations of <i>In Situ</i> Particle Monitors in Silicon Processing Equipment," <i>J. Vac. Sci.Technol.</i> , November/December 1996, A 14, (6) pp. 2983-2993, American Vacuum Society.		
ma		SELWYN, G.S. et al., "Particle Contamination Formation in Magneton Sputtering Processes," J. Vac. Sci. Technol, July/August 1997, A 15 (4), pp. 2023-2028, American Vacuum Society.		
MA		MONTEIRO, O.R. et al., "Vacuum-Arc-Generated Macroparticles in the Nanometer Range," <i>IEEE Transactions on Plasma Science</i> , August 1999, Vol. 27, No. 4, pp. 1030-1033, IEEE.		
M		ABBURI, M. et al., "Low-Defect Target Metallurgy Development for sub-0.18µm Al-based Interconnects," <i>Solid State Technology</i> , December 1999, Vol. 42, pp. 55-58, Solid State Technology.		

Examiner Signature	melogn and sew	Date

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